

REMARKS

At the outset, Applicant thanks the Examiner for withdrawing the rejection of claims 3-8, 10-21, 23, and 67-70 under 35 U.S.C. §102(b) as being anticipated by U.S. Patent No. 6,036,583 to *Aizawa et al.* (hereinafter "*Aizawa*"). See Advisory Action of January 20, 2006.

Claims 67 and 70 are hereby amended. Claims 1 and 2 were previously canceled. Claims 24-66 were previously withdrawn. Accordingly, claims 3-23 and 67-70 are currently pending. Reexamination and reconsideration are respectfully requested.

In the Office Action, claims 3-8, 10-21, 23, and 67-70 were rejected under 35 U.S.C. § 103(a) as being unpatentable over *Aizawa et al.* in view of U.S. Patent No. 6,267,549 to *Brown et al.* (hereinafter "*Brown*"). Applicant traverses the rejection.

As required in Chapter 2143.03 of the M.P.E.P., in order to establish *prima facie* obviousness of the claimed invention, all the limitations must be taught or suggested by the prior art. Applicant submits that *Aizawa* and *Brown*, taken singularly or in combination, fail to disclose or suggest all the features recited in claims 3-8, 10-21, 23, and 67-70.

More specifically, claim 67 recites a system for polishing objects comprising, inter alia, a "first transfer robot configured to transfer one of said objects to the polishing unit, the second transfer robot being configured to transfer another of said objects to the polishing unit, the first and second transfer robots being positioned on a surface such that a center axis of the first transfer robot is offset from a center axis of the second transfer robot, wherein the center axis of the first transfer robot and the center axis of the second transfer robot are transverse to the surface."

Aizawa fails to disclose at least first and second transfer robots, as recited in the claims. More specifically, pusher 34, as disclosed by *Aizawa*, fails to anticipate or render

obvious a first or a second transfer robot, as recited. In contrast, *Aizawa* discloses that polishing units 10a, 10b comprise pushers 34, which transfer semiconductor wafers to and from the top ring 30 and are vertically movable. See column 5, lines 14-26 and Figures 1-2 of *Aizawa*. In other words, pushers 34 of *Aizawa* are within chambers R4, R5 (i.e., polishing units 10a, 10b). That is, a pusher 34, as disclosed by *Aizawa*, transfers a wafer “within” polishing unit 10a or 10b, namely to and from top ring 30. However, pushers 34 of *Aizawa* do not transfer objects “to” and/or “from” polishing unit 10a or 10b.

Furthermore, *Brown* fails to supply the deficiencies of *Aizawa*. More specifically, *Brown* fails to disclose first and second transfer robots that transfer objects to a polishing unit, as recited in the claims. Moreover, *Brown* does not even disclose a polishing unit, and thus also fails to disclose a robot transferring to and/or from a polishing unit.

In addition, *Brown* fails to disclose or suggest, inter alia, “the first and second transfer robots being positioned on a surface such that a center axis of the first transfer robot is offset from a center axis of the second transfer robot, wherein the center axis of the first transfer robot and the center axis of the second transfer robot are transverse to the surface,” as recited in claim 67. Rather, as shown in at least Figures 1 and 3, *Brown* discloses a robot system in which a first robot 12 is coaxially aligned with a second robot 20.

Accordingly, claim 67 is patentable over the applied references. Accordingly, Applicant requests that the rejection be withdrawn. Similarly, claims 3-8, 10-21, 23, and 68-69, which variously depend from claim 67, are also patentable for at least the same reasons as discussed above.

Claim 70 recites a system for polishing surfaces of semi-conductor wafers comprising, inter alia, a “first transfer robot and the second transfer robot both being configured

to transfer semi-conductor wafers to the polishing unit, wherein the second transfer robot is configured to transfer semi-conductor wafers from the polishing unit to a post-polishing unit wherein the first transfer robot and the second transfer robot cooperatively transfer the semi-conductor wafers to and from the polishing unit to efficiently process the semi-conductor wafers through the polishing unit, wherein the first and second transfer robots are positioned on a surface such that a center axis of the first transfer robot is offset from a center axis of a second transfer robot, the center axis of the first transfer robot and the center axis of the second transfer robot being transverse to the surface.”

As previously discussed, the applied references, taken singularly or in combination, fail to disclose or suggest such features. Thus, claim 70 is patentable over *Aizawa* in view of *Brown*. Accordingly, Applicant requests that the rejection be withdrawn.

Further, claims 9 and 22 were rejected under 35 U.S.C. §103(a) as being unpatentable over *Aizawa* in view of U.S. Patent No. 5,948,203 to *Wang* (hereinafter “*Wang*”). Applicant traverses this rejection.

Applicant respectfully submits that *Aizawa* and *Wang*, taken alone or in combination, fail to disclose each and every element recited in claims 9 and 22. As discussed above, *Aizawa* fails to disclose each and every element of claim 67, from which claims 9 and 22 depend. Furthermore, *Wang* fails to address the previously noted shortcomings discussed with reference to *Aizawa*. As such, Applicant respectfully submits that claims 9 and 22 are patentable over *Aizawa* in view of *Wang* under 35 U.S.C. §103(a) and requests that the rejection be withdrawn.

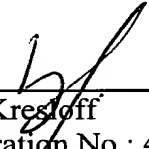
The application is in a condition for allowance and favorable action is respectfully solicited. If for any reason the Examiner believes a conversation with the Applicant’s representative would facilitate the prosecution of this application, the Examiner is encouraged to

contact the undersigned attorney at (202) 496-7500. All correspondence should continue to be sent to the below-listed address.

If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time, or any other fees required to complete the filing of this response, may be charged to Deposit Account No. 50-0911. Please credit any overpayment to deposit Account No. 50-0911. A duplicate copy of this sheet is enclosed.

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Respectfully submitted,

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